



Sheet 1 of 2

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Form PTO-1449

INFORMATION DISCLOSURE CITATION  
IN AN APPLICATION

(Use several sheets if necessary)

Docket Number, Optional  
16139/09002-CON

Application Number

10/057,920

Applicant

Michael L. Myrick

Filing Date

January 25, 2002

Group Art Unit

2633

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
MRJ	4	0	8	4	8	8	0	04/18/1978	Clow	350	3.72	
MRJ	4	1	1	8	1	0	6	10/03/1978	Leith	350	96.25	
MRJ	4	6	8	7	3	3	5	08/18/1987	Zupanick, et al.	356	416	
MRJ	4	8	2	1	3	3	8	04/11/1989	Naruse, et al.	455	617	
MRJ	4	9	3	4	7	8	2	06/19/1990	Soffer, et al.	350	162.12	
MRJ	5	0	0	5	9	4	6	04/09/1991	Brandstetter	350	162.12	
MRJ	5	0	2	9	2	4	5	07/02/1991	Keranen, et al.	250	205	
MRJ	5	0	9	0	8	0	7	02/25/1992	Tai	356	310	
MRJ	5	1	9	4	9	2	1	03/16/1993	Tambo, et al.	356	432	
MRJ	5	2	8	9	2	8	9	02/22/1994	Nagasaki	358	432	
MRJ	5	3	2	1	5	3	9	06/14/1994	Hirabayashi, et al.	359	94	
MRJ	5	4	1	2	4	6	5	05/02/1995	Baylor, et al.	356	301	
MRJ	5	4	2	4	5	4	5	06/13/1995	Block, et al.	250	343	
MRJ	5	4	5	9	6	7	7	10/17/1995	Kowalski, et al.	364	571.02	
MRJ	5	4	7	9	1	6	4	12/26/1995	Yorks, et al.	341	50	
MRJ	5	5	1	3	0	2	2	04/30/1996	Son, et al.	359	16	
MRJ	5	5	5	5	1	2	8	09/10/1996	Khoury, et al.	359	559	

## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	Translation	
												YES	NO
MRJ	0	4	0	0	1	5	5	8	07/01/1992	Japan			X
MRJ	0	6	0	0	3	3	4	A2	11/22/1993	Europe			X
MRJ	1	1	5	0	6	2	0	6	02/06/1999	Japan			X
MRJ	1	1	5	0	6	2	0	7	02/06/1999	Japan			X
WO MRJ	9	6	3	0	7	4	6		10/03/1996	PCT		X	

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

MRJ	Photographs of Buhler System
MRJ	J.A. Dobrowolski and R.A. Kemp, "Refinement of Optical Multilayer Systems With Different Optimization Procedures," Applied Optics, Vol. 29; No. 19, July 1990, pp. 2876-93
MRJ	Brian T. Sullivan and J.A. Dobrowolski, "Implementation of Numerical Needle Method for Thin-Film Design," Applied Optics, Vol. 35; No. 28, October 1996, pp. 5484-92
MRJ	A.G. Ryabenko and G.G. Kasparov, "An Algorithm for Constructing the Basis of Optimal Linear Combinations. Spectral Determination of Aerosol Impurities against the Background of a Water Aerosol with an Arbitrary Particle Size Distribution," Pattern Recognition and Image Analysis, Vol. 3; No. 1, March 1993, pp. 348-54

EXAMINER

M.R. SEDIGHIAN

DATE CONSIDERED

7/25/03

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

Form 230-1449

## INFORMATION DISCLOSURE CITATION IN AN APPLICATION

*(Use several sheets if necessary)*

**Docket Number Optional**  
16139/09002-CON

Application Number 10/057,040

**Applicant**

Michael L. Myrick

**Filing Date**  
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**Group Art Unit** 2633

## U.S. PATENT DOCUMENTS

[illegible]

## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER								DATE	COUNTRY	CLASS	SUBCLASS	Translation	
													YES	NO

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

MR)	A.G. Ryabenko and G.G. Kasparov , "Numerical Study of a Pattern Recognition Multispectral System with Optimal Spectral Splitting," <u>Pattern Recognition and Image Analysis</u> , Vol. 1; No. 3, 1991, pp. 57-68
MR)	Vasil'ev, et al, "Rotational and Vibrational Deactivation of Excited HF Molecules," <u>Sov. Physics - JETP</u> , Vol. 41; No. 4, 1976, pp. 617-21
MR)	Moravskii, et al., "Spectrophotometric Determination of the Yield of the C <sub>60</sub> and C <sub>70</sub> Fullerenes in Electric Arc Synthesis under Helium," <u>Journal of Analytical Chemistry</u> , Vol. 53; No. 12, 1998, pp. 1135-42
MR)	International Search Report, January 19, 1999.
MR)	International Search Report; January 21, 2000.
MR)	Patent application serial no. 09/286,881 entitled "Optical Computational System," filed April 6, 1999.

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